

Attorney Docket No. NTI-703-1P1P

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Linyong Pang, et al.

Art Unit: 2825

Serial Number: 10/618,816

Examiner: Vuthe Siek

Filing Date: 07/11/2003

Title "System And Method For Providing Defect Printability Analysis Of Photolithographic Masks With Job-Based Automation"

Date: June 29, 2005

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REQUEST FOR CORRECTED FILING RECEIPT

Sir:

There is an error with respect to the following:

Error in

Correct data

Domestic Priority Data

which is a CIP of 09/130,996 8/7/1998 PAT 6,757,645

A copy of the Filing Receipt with the changes noted thereon is enclosed. Issuance of a corrected Filing Receipt is respectfully requested.

Respectfully submitted,

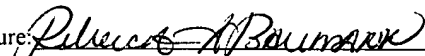
Dated: June 29, 2005

By: 

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I hereby certify that this correspondence is being deposited with the United States Postal Service as FIRST CLASS MAIL in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450, on June 29, 2005.

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/618,816	07/11/2003	2825	1554	NTI-703-1P1P	11	60	4

CONFIRMATION NO. 5976

FILING RECEIPT



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29477
 NUMERICAL
 C/O BEVER HOFFMAN & HARMS, LLP
 2099 GATEWAY PLACE
 SUITE 320
 SAN JOSE, CA 95110-1017

Date Mailed: 10/10/2003

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Applicant(s)

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 LOS ALTOS

Assignment For Published Patent Application

Numerical Technologies, Inc.;

Domestic Priority data as claimed by applicant

This application is a CIP of 10/372,066 02/20/2003
 which is a DIV of 09/544,798 04/07/2000 PAT 6,578,188
~~which is a CIP of 09/154,397 09/16/1998 PAT 6,453,452~~
 which claims benefit of 60/059,306 09/17/1997

(*)Data provided by applicant is not consistent with PTO records.

which is a CIP of 09/130,996
 8/1/1998 PAT 6,757,645

Foreign Applications

If Required, Foreign Filing License Granted: 10/09/2003

Projected Publication Date: 01/22/2004

Non-Publication Request: No

Early Publication Request: No

Title

System and method for providing defect printability analysis of photolithographic masks with job-based automation

Preliminary Class

716

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